

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In the Application of:)	
)	
Noriaki Fukiage)	Examiner: LaFond, Ronald D.
)	
Serial No. 10/812,354)	Art Unit: 1709
)	
Filed: 03/30/2004)	
)	
For: Method of Improving the Wafer to Wafer Uniformity)	
and Defectivity of a Deposited Dielectric Film)	

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

AMENDMENT AND REQUEST FOR RECONSIDERATION

Dear Sir:

Responsive to the Office Action mailed 06/27/2007, the Applicant requests the Examiner to reconsider all pending claims in view of the following amendments and remarks.